



## Advanced MEMS/NEMS Technology

Guest Editors:

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**Prof. Da-Jeng Yao**

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Deadline for manuscript  
submissions:

**closed (20 November 2018)**

### Message from the Guest Editors

Dear Colleagues,

The 13th International Conference on Nano/Micro Engineered and Molecular Systems (NEMS) will be held 22–26 April, 2018, at the Grand Hyatt, Singapore. NEMS is a premier conference series sponsored by the IEEE Nanotechnology Council, focusing on the promotion of advanced research areas related to MEMS, nanotechnology, and molecular technology. Micromachines is the leading journal in the MEMS and NEMS fields. We want to consolidate original research papers and comprehensive review articles in this Special Issue. We welcome manuscripts on the following topics:

- Micro/Nanomachines
- Optical MEMS and Nanophotonics
- RF MEMS, Resonators and Oscillators
- Ultrasound MEMS (pMUT and cMUT)
- Energy Harvesting Technology
- BioMEMS and Biomedical Devices
- Neuroprosthetics and Implanted Devices
- Micro/Nanofluidics
- Soft materials and robotics
- Chemical Sensors/Gas Sensors/Sensors for environmental Monitoring
- Sensor Network/IoT





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## Editor-in-Chief

## Message from the Editor-in-Chief

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